

PROBING DEVICE AND MANUFACTURING METHOD THEREOF

ABSTRACT

5 A probing device and manufacturing method thereof are provided. The
manufacturing method includes the following steps. First, a plurality of space
transformers is disposed on a reinforcing plate and the space transformer includes a
plurality of first pads. Then, the space transformer is fixed on the reinforcing plate.
Thereafter, a plurality of photoresist films having a plurality of openings is formed on
10 the space transformer. The first pads are disposed in the openings. After that, a metal
layer is formed and covered on the first pad. Later, the photoresist film is removed
and the metal layer planarized to form a second pad. Afterwards, the reinforcing plate
is electrically connected with a PCB. Thereafter, a probe head having a plurality of
probing area is provided and each probing area is corresponding to one of the space
15 transformer. The probes in the probing area are electrically connected with the internal
circuitry of the space transformer.

(Fig. 3)